Amendments to the Claims:

This listing of claims will replace all prior versions and listings of claims in the application.

Listing of Claims:

What is claimed is:

Claim 1 (Currently Amended): An apparatus for closing a chamber, the chamber having a first 1 chamber housing and a second chamber housing, comprising: 2 means for forming a chamber including means for bringing the first chamber 3 housing into contact with the second chamber housing such that the chamber is 4 configured for sustaining supercritical fluid; and 5 deforming means for preventing formation of particles while the first chamber 6 housing contacts the second chamber housing, wherein the deforming means is mounted 7 8 on at least one of the first chamber housing and the second chamber housing such that it deforms to accommodate any misalignment while the means for forming a chamber 9 10 operates. Claim 2 (Original): The apparatus of claim 1 wherein the first chamber housing includes a first 1 2 interior surface defining a first cavity. Claim 3 (Original): The apparatus of claim 2 wherein the first interior surface defining a first 1 2 cavity is sized to contain a semiconductor wafer for forming integrated circuits. 1 Claim 4 (Original): The apparatus of claim 2 wherein the second chamber housing includes a 2 second interior surface defining a second cavity. Claim 5 (Original): The apparatus of claim 4 wherein the second interior surface defining a 1 2 second cavity is sized such that when juxtaposed with the first cavity a region thereby 3 formed is sufficiently sized to contain a semiconductor wafer for forming integrated 4 circuits.

2	structure for stabilizing the first chamber housing while the first chamber housing
3	contacts the second chamber housing.
l	Claim 7 (Original): The apparatus of claim 6 wherein the second chamber housing is driven by
2	motivating structure, being constructed and arranged to move the second chamber
3	housing in and out of contact with the first chamber housing.
l	Claim 8 (Original): The apparatus of claim 7 wherein the motivating structure is powered by at
<u>)</u>	least one of a pneumatic source, a hydraulic source, a turbine, and a motor.
[Claim 9 (Original): The apparatus of claim 7 wherein the motivating structure comprises:
2	a body defining a casing; and
3	a moveable member, being positioned in the casing and being reciprocable along
1	an axis between a first position and a second position, wherein the second chamber
5	housing contacts the first chamber housing while the moveable member is in the first
5	position, and wherein the second chamber housing is not in contact with the first chamber
7	housing while the moveable member is in the second position.
	Claim 10 (Original): The apparatus of claim 9 wherein the deforming means comprises at least
2	one of a material between a surface of the first chamber housing and a surface of the
3	structure to which the first chamber housing is mounted, a material between a surface of
1	the second chamber housing and a surface of the motivating structure, and a material
5	between a surface of the moveable member and a surface of the casing.
	Claim 11 (Original):The apparatus of claim 10 wherein the material comprises an abrasion
2	resistant material characterized by high impact strength and having a low coefficient of
3	friction.
ĺ	Claim 12 (Original): The apparatus of claim 10 wherein the material comprises at least one of
2	polyether ether ketone (PEEK™), thermoplastic resin, polyolefin type resin, polyamide
3	resin, polyester resin, polyether resin, polynitrile resin, polymethacrylate resin, polyvinyl

} ;	resin, cellulose resin, fluorine resin and a composition of PEEK TM and at least one of resins and fillers.
	Claim 13 (Withdrawn): The apparatus of claim 1 further comprising alignment means for
2	reducing an amplitude of relative motion between the first chamber housing and the
3	second chamber housing while the first chamber housing contacts the second chamber
ļ	housing.
5	Claim 14 (Withdrawn): The apparatus of claim 13 wherein the alignment means comprises a
5	first chamber housing feature adapted to engage with a second chamber housing feature
7	to particularly position the second chamber while the first chamber housing contacts the
3	second chamber housing.
l .	Claim 15 (Withdrawn): The apparatus of claim 14 wherein at least one of the first chamber
2	housing feature and the second chamber housing feature comprises a protrudance,
3	wherein the protrudance has a particularly shaped outer edge adapted to interfit with a
1	recess defined in at least one of the first chamber housing and the second chamber
5	housing.
l·	Claim 16 (Withdrawn): The apparatus of claim 13 wherein the alignment means comprises a
2	pin-like structure located on at least one of the first chamber housing and the second
3	chamber housing and an aperture defined in at least one of the first chamber housing and
1	the second chamber housing to securely receive the pin-like structure.
l	Claim 17 (Withdrawn): The apparatus of claim 16 wherein the aperture is elongated in shape
2	and has at least one chamfered inner wall adapted to facilitate alignment of the aperture
3	with the pin-like structure.
1	Claim 18 (Withdrawn): The apparatus of claim 1 wherein at least one of the first chamber
2	housing and the second chamber housing comprises a manifold having thereon a plurality
3	of fluid outlets for distributing a process fluid.

1 2	Claim 19 (Withdrawn): The apparatus of claim 1 further comprising means for performing a supercritical process.
1 2	Claim 20 (Withdrawn): The apparatus of claim 19 wherein the means for performing a supercritical process comprises means for circulating at least one of gaseous, liquid, supercritical and near-supercritical carbon dioxide in the chamber.
1	Claim 21 (Withdrawn): A method of closing a chamber, the chamber having a first chamber
2	housing and a second chamber housing, comprising the steps of:
3 4	a. forming a chamber including bringing the first chamber housing into contact with the second chamber housing; and
5 6	b. preventing formation of particles while the first chamber housing contacts the second chamber housing.
1	Claim 22 (Withdrawn): The method of claim 21 wherein the step of forming a chamber
2	comprises moving the second chamber housing in and out of contact with the first
3	chamber housing.
1	Claim 23 (Withdrawn): The method of claim 21 wherein the step of preventing formation of
2	particles comprises positioning a material on at least one of the first chamber housing and
3	the second chamber housing such that the material deforms to accommodate any
4	misalignment while forming a chamber.
1	Claim 24 (Withdrawn): The method of claim 23 wherein the material comprises an abrasion
2	resistant material characterized by high impact strength and having a low coefficient of
3	friction.
1	Claim 25 (Withdrawn): The method of claim 23 wherein the material comprises at least one of
2	polyether ether ketone (PEEK TM), thermoplastic resin, polyolefin type resin, polyamide
3	resin, polyester resin, polyether resin, polynitrile resin, polymethacrylate resin, polyvinyl
4	resin, cellulose resin, fluorine resin and a composition of PEEK™ and at least one of
5	resins and fillers.

	Claim 26 (Withdrawn): The method of claim 21 wherein the step of preventing formation of
	particles comprises configuring an alignment means for reducing an amplitude of relative
\$ ‡	motion between the first chamber housing and the second chamber housing while the first chamber housing contacts the second chamber housing.
Ì	Claim 27 (Withdrawn): The method of claim 26 wherein the step of employing an alignment
)	means comprises configuring a first-chamber-housing feature to engage with a second-
- }	chamber-housing feature to particularly position the second chamber while the first
1	chamber housing contacts the second chamber housing.
5	Claim 28 (Withdrawn): The method of claim 21 further comprising processing an object with a
5	fluid.
l	Claim 29 (Withdrawn): The method of claim 28 wherein the step of processing an object with a
2	fluid comprises processing a semiconductor wafer with at least one of gaseous, liquid,
3	supercritical and near-supercritical carbon dioxide.
l	Claim 30 (Withdrawn): A method of eliminating particle generation at a platen/injection ring
2	interface, comprising the steps of:
3 4	a. forming a platen/injection ring interface including bringing a platen into contact with an injection ring; and
5	b. positioning a material on at least one of the injection ring and the platen such that
5	the material deforms to accommodate any misalignment while forming the
7	platen/injection ring interface.
1	Claim 31 (Withdrawn): A method of 30 further comprising the step of configuring an alignment
2	means for reducing an amplitude of relative motion between the platen and the injection
3	ring while the platen contacts the injection ring.
l	Claim 32 (Withdrawn): The method of claim 30 further comprising the step of processing a
2	semiconductor wafer with at least one of gaseous, liquid, supercritical and near-
3	supercritical carbon dioxide.

PATENT
Attorney Docket No.: SSI-08100

1	Claim 33 (New): An apparatus for closing a chamber, the chamber having a first chamber
2	housing and a second chamber housing, comprising:
3	means for forming a chamber including means for bringing the first chamber
4	housing into contact with the second chamber housing; and
5	deforming means for preventing formation of particles while the first chamber
6	housing contacts the second chamber housing, wherein the deforming means is mounted
7	on at least one of the first chamber housing and the second chamber housing such that it
8	deforms to accommodate any misalignment while the means for forming a chamber
9	operates wherein at least one deforming means is positioned to deform in a direction
10	substantially orthogonal to a chamber contact motivating force.
1	Claim 34 (New): The apparatus of claim 33 wherein the first chamber housing is mounted to a
2	structure for stabilizing the first chamber housing while the first chamber housing
3	contacts the second chamber housing.
1	Claim 35 (New): The apparatus of claim 34 wherein the second chamber housing is driven by a
2	motivating structure, being constructed and arranged to move the second chamber
3	housing in and out of contact with the first chamber housing.
1	Claim 36 (New): The apparatus of claim 35 wherein the motivating structure comprises:
2	a body defining a casing; and
3	a moveable member, being positioned in the casing and being reciprocable along
4	an axis between a first position and a second position, wherein the second chamber
5	housing contacts the first chamber housing while the moveable member is in the first
6	position, and wherein the second chamber housing is not in contact with the first chamber
7	housing while the moveable member is in the second position.
1	Claim 37 (New): An apparatus for closing a chamber, the chamber having a first chamber
2	housing and a second chamber housing, comprising:
3	means for forming a chamber including means for bringing the first chamber
4	housing into contact with the second chamber housing; and
5	deforming means for preventing formation of particles while the first chamber

PATENT Attorney Docket No.: SSI-08100

5	housing contacts the second chamber housing, wherein the deforming means is mounted
7	on at least one of the first chamber housing and the second chamber housing such that it
3	deforms to accommodate any misalignment while the means for forming a chamber
)	operates wherein the deforming means comprises of polyether ether keton (PEEK TM).
l	Claim 38 (New): The apparatus of claim 37 wherein the first chamber housing is mounted to a
2	structure for stabilizing the first chamber housing while the first chamber housing
3	contacts the second chamber housing.
1	Claim 39 (New): The apparatus of claim 38 wherein the second chamber housing is driven by a
2	motivating structure, being constructed and arranged to move the second chamber
3	housing in and out of contact with the first chamber housing.
1	Claim 40 (New): The apparatus of claim 39 wherein the deforming means comprises at least one
2	of a material between a surface of the first chamber housing and a surface of the structure
3	to which the first chamber housing is mounted, a material between a surface of the second
4	chamber housing and a surface of the motivating structure, and a material between a
5	surface of the moveable member and a surface of the casing.